

Single crystal cells

silicon cells:

basic design

fabrication

strategies for high efficiency

light management

minimising resistive losses

minimizing recombination losses

GaAs cells

basic design

problems

special applications

Silicon cells

- ❑ single crystal: efficiency η up to 24.7% (module 22.7%)
- ❑ multicrystalline: η ~20 % (module 15%)
- ❑ a-Si: η ~10%

photovoltaic-grade Si properties:

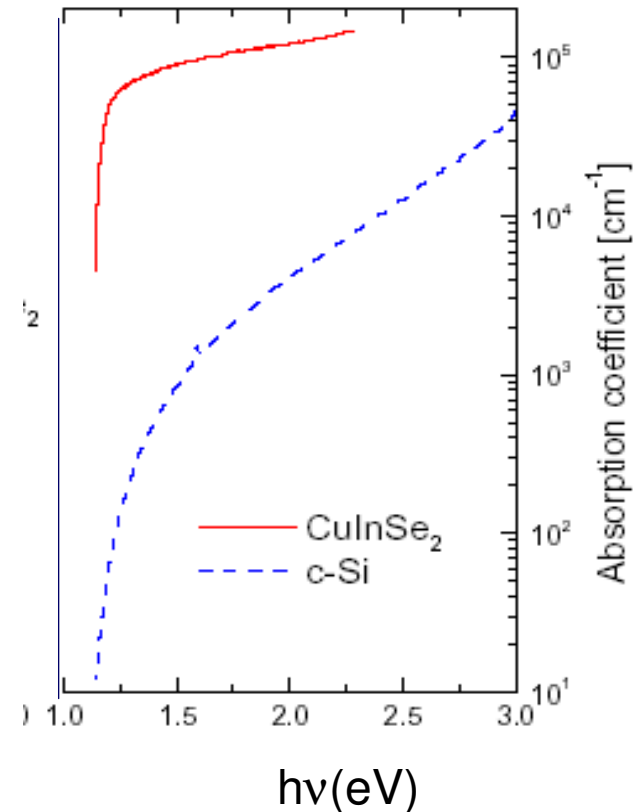
doping $\sim 10^{16} \text{ cm}^{-3}$

mobility $\sim 1000 \text{ cm}^2/\text{Vs}$

minority carrier diffusion length $100 \mu\text{m}$

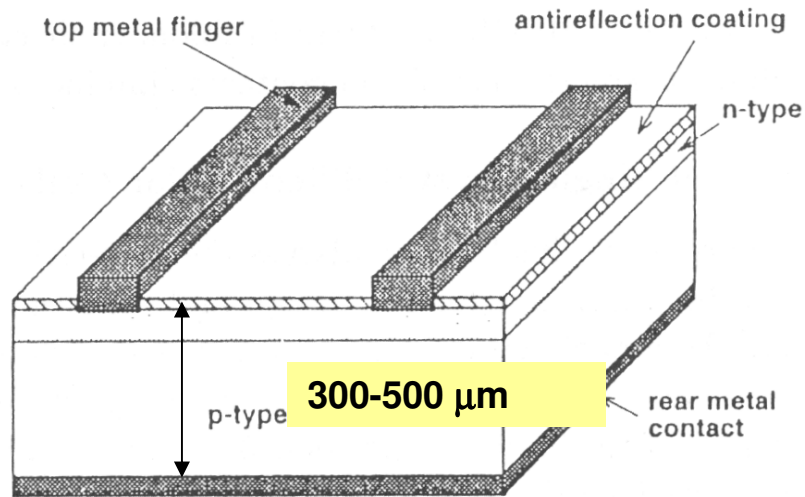
sheet resistance $0.1 \Omega\text{cm}^2$ (for $d= 500 \mu\text{m}$)

indirect bandgap – poor absorption

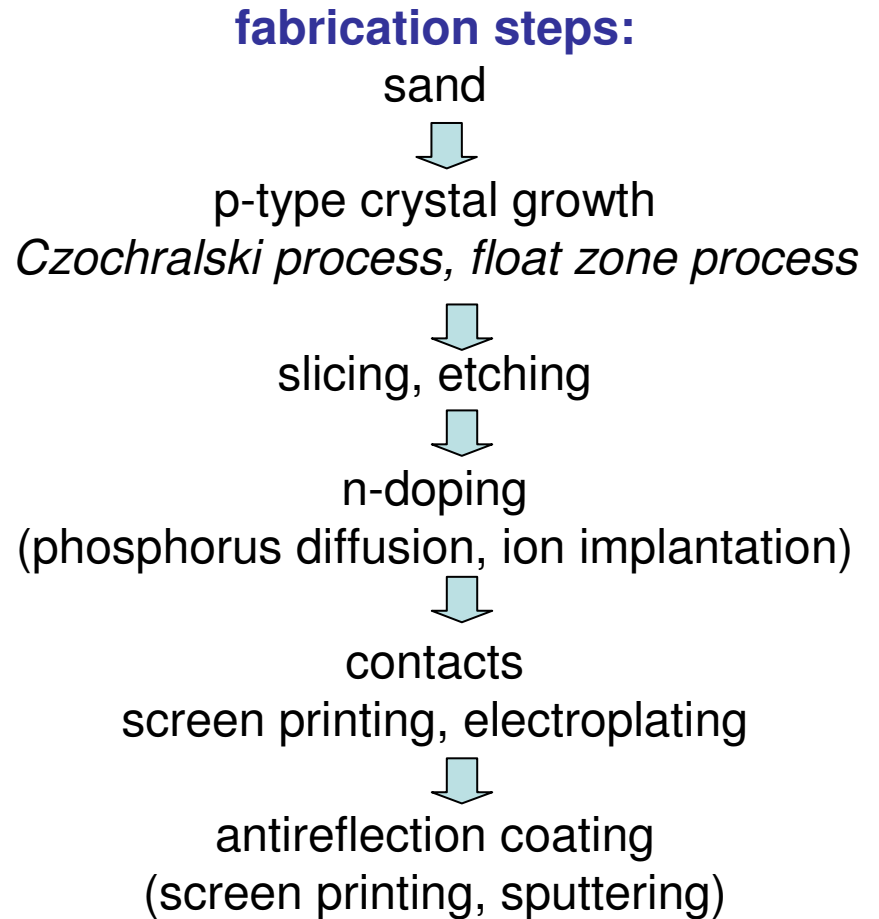


$\exp(\alpha d) \gg 1$ for $d > 200 \mu\text{m}$

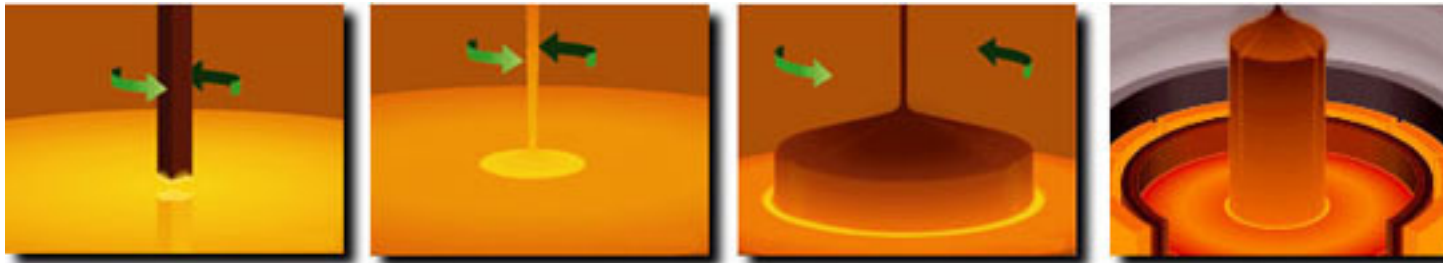
Monocrystalline silicon



standard
 $\eta = 15 - 18 \%$



Czochralski process of c-Si growth



boron-doped during growth



Single Crystal Silicon Ingot

d ~ 15 cm



CZ Crystal Pullers
(Mitsubishi Materials Silicon)

Typical Si cell parameters

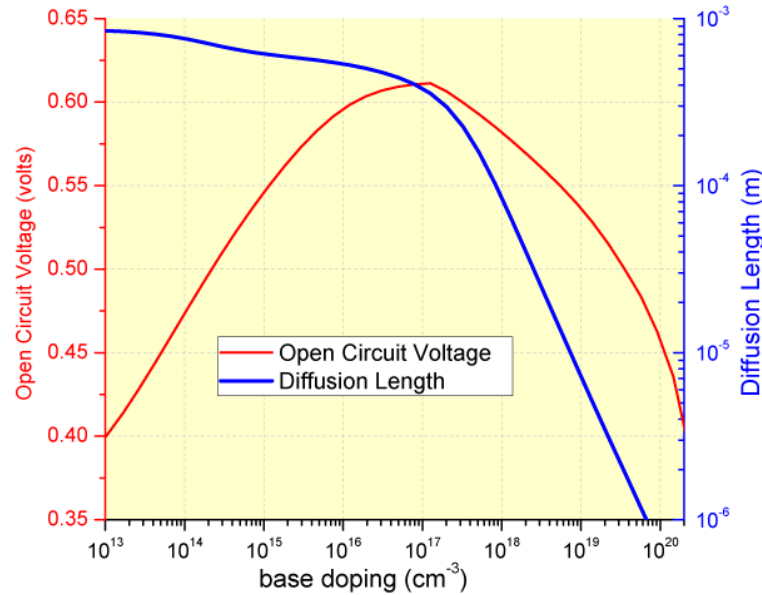
	emitter n-type	base p-type
thickness	0.5 μm	300 μm
doping	10^{19} cm^{-3}	10^{16} cm^{-3}
minority carrier diffusion length	14 μm	140 μm
minority carrier lifetime	10^{-6} s	$5 \times 10^{-6} \text{ s}$

Problems:

- poor absorption of long-wavelength photons
- rear surface recombination
- series resistance

Optimisation of the cell design

doping vs recombination losses



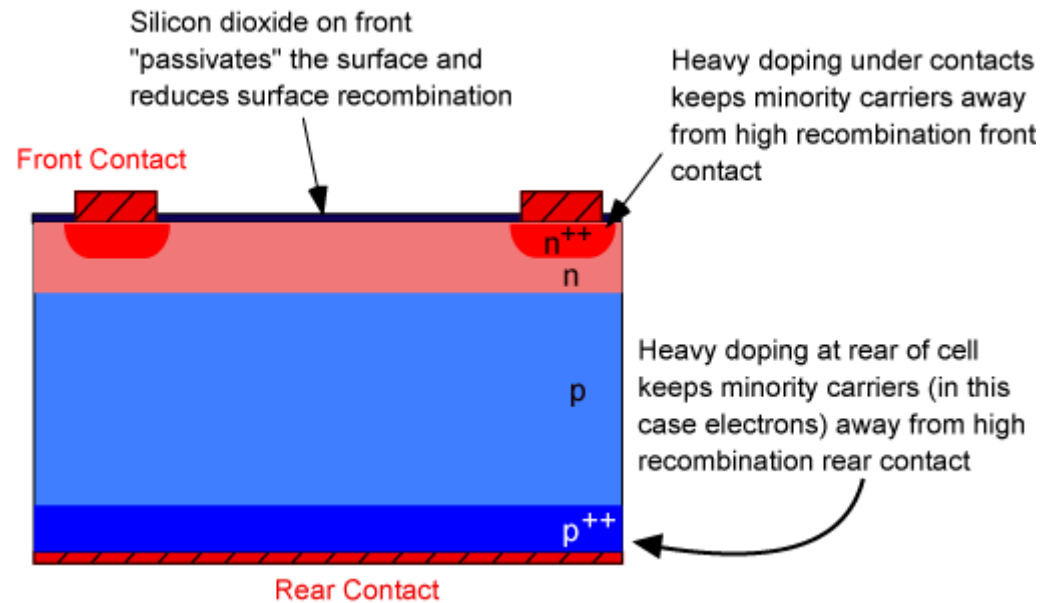
Optimisation of the cell structure:

low series resistance → high doping of emitter → low diffusion length in the emitter

shallow junction necessary to avoid „dead layer” effect

reduction of the front surface recombination necessary

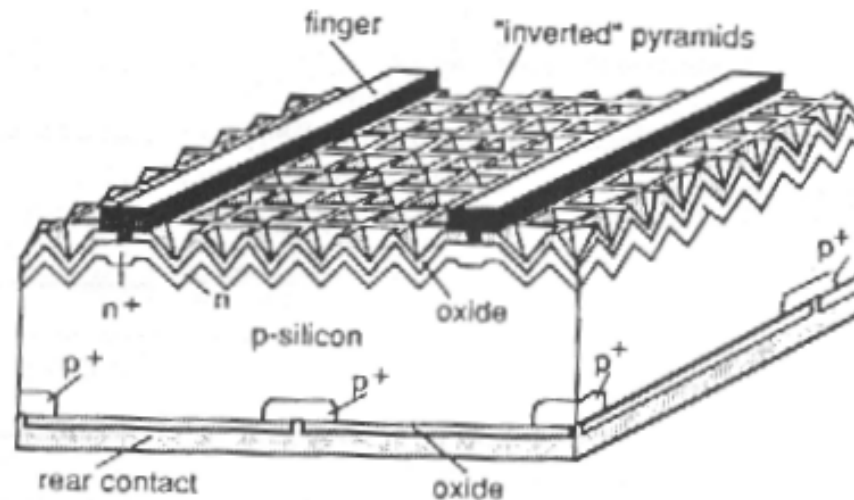
Reducing recombination at front and back electrode



passivation of the front surface (oxides, nitrides)
high doping close to the electrical contacts

Strategies for high efficiency

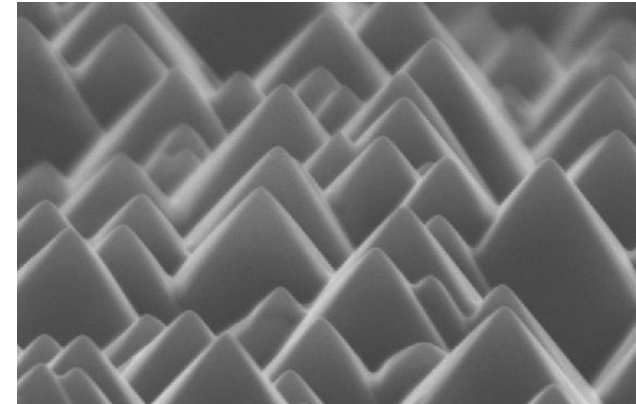
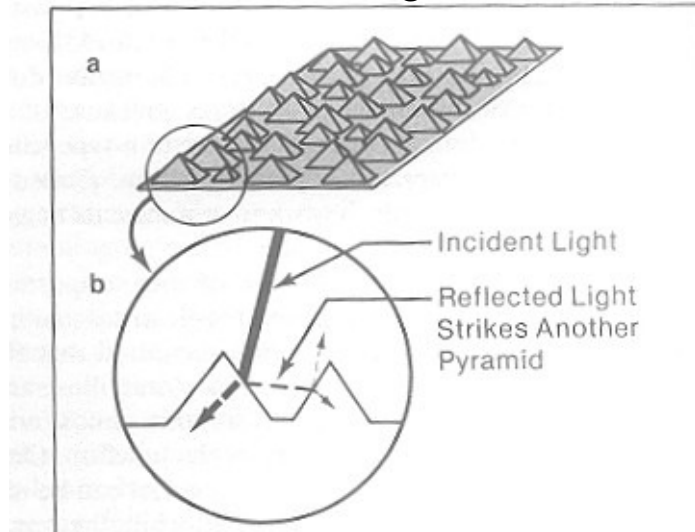
- ❑ enhance absorption – antireflective coating, texturing
- ❑ contacts optimization - buried contacts
- ❑ reduce surface recombination - back surface field, passivation of front and back contacts, rear point contacts



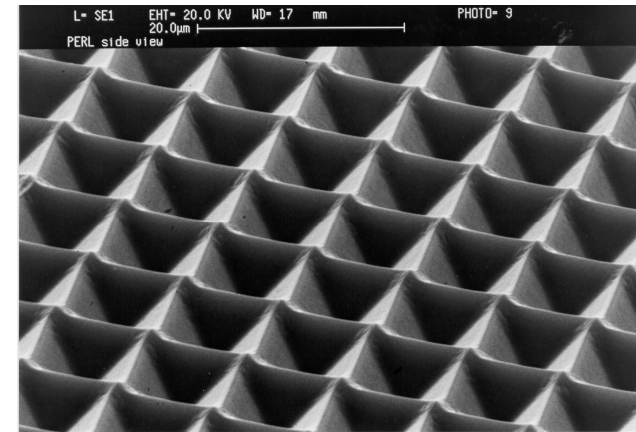
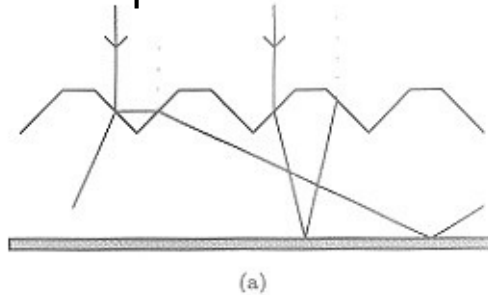
PEARL cell (*Passivated Emiter, Rear Locally-Difused*) $\eta = 24,4 \%$

Maximise absorption - texturing

etching



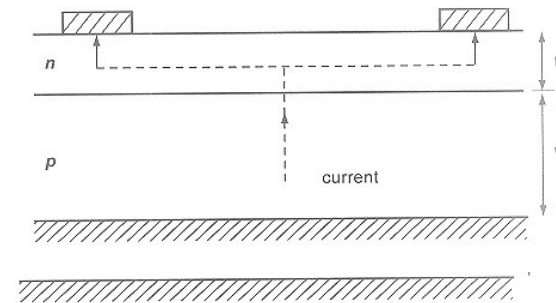
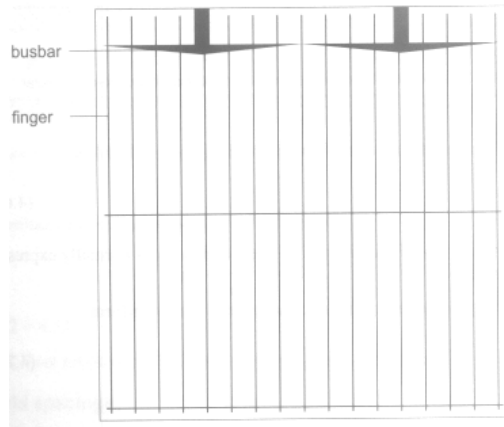
inverted pyramids
– improve reflection



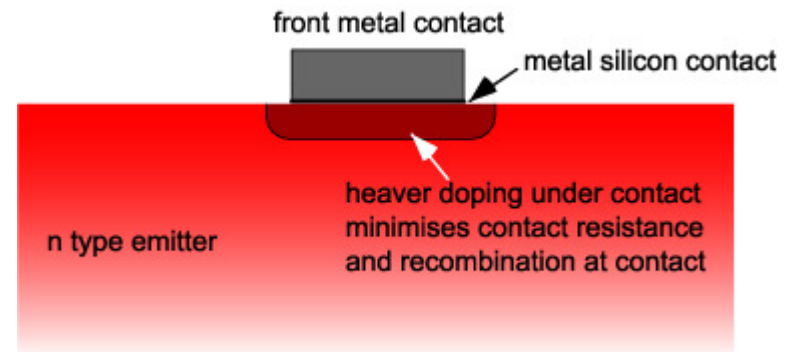
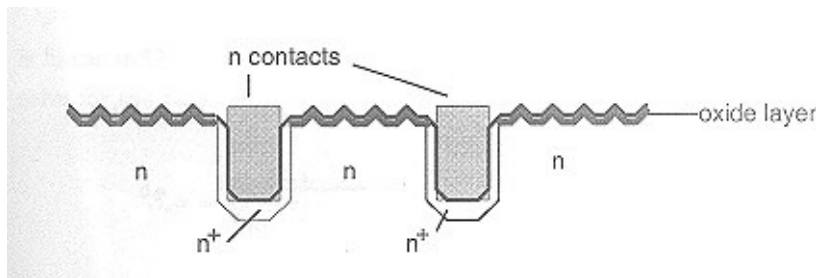
Light trapping

Maximise absorption and minimise series resistance

optimisation of grid fingers



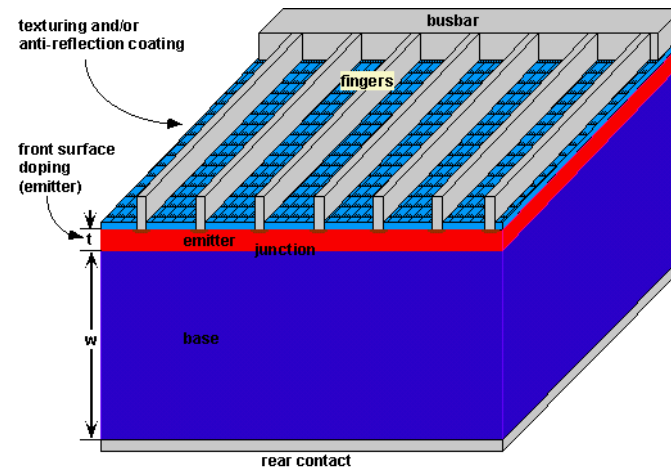
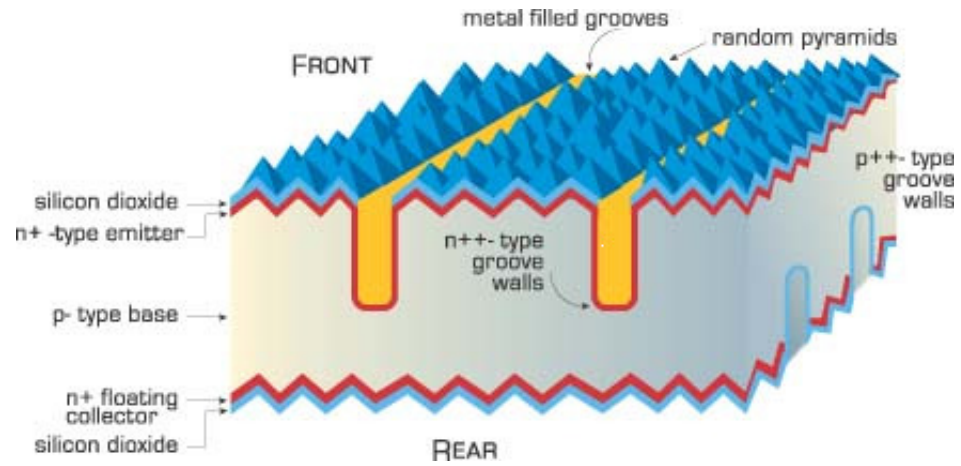
**Important: sheet resistance ρ/t
grid spacings**



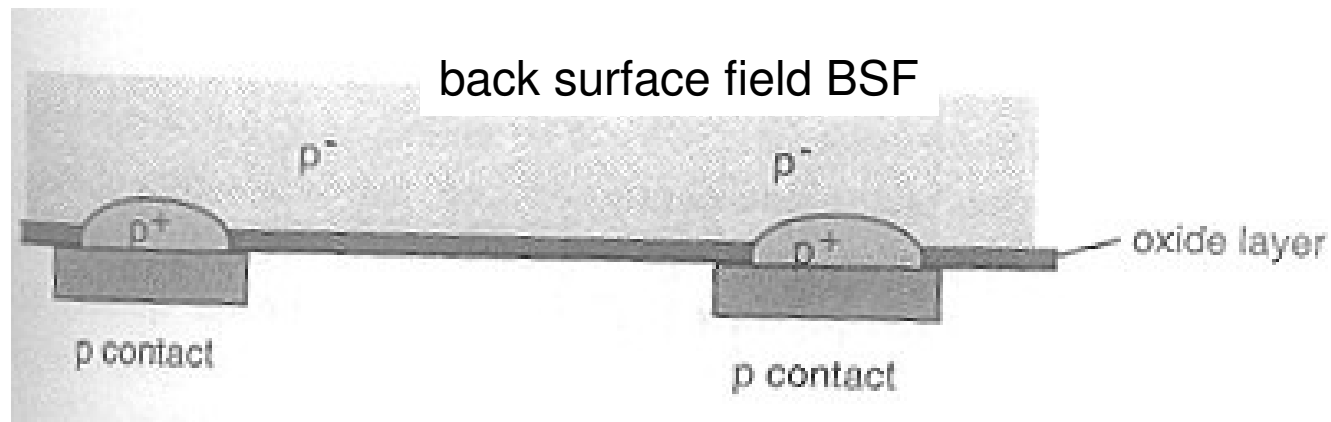
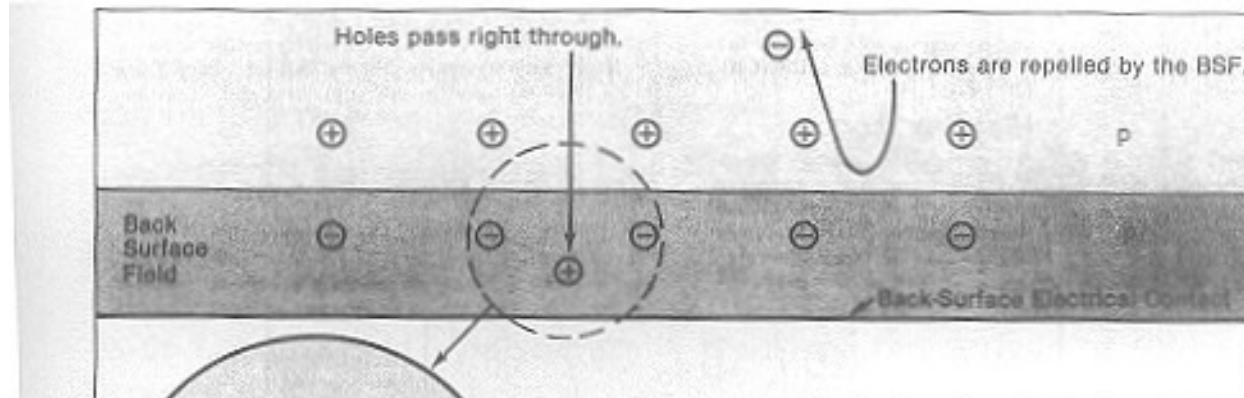
„buried contacts” : minimised shaded area, large contact area

Costs!

buried contacts cell



Minimise back contact recombination



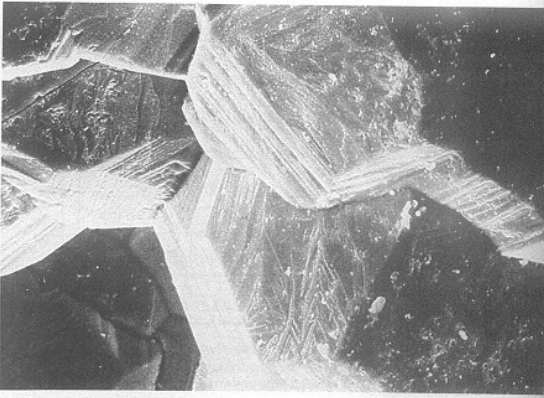
rear point contact cell

- ✓ **passivation of the back surface with oxide**
- ✓ **differential doping close to contacts**

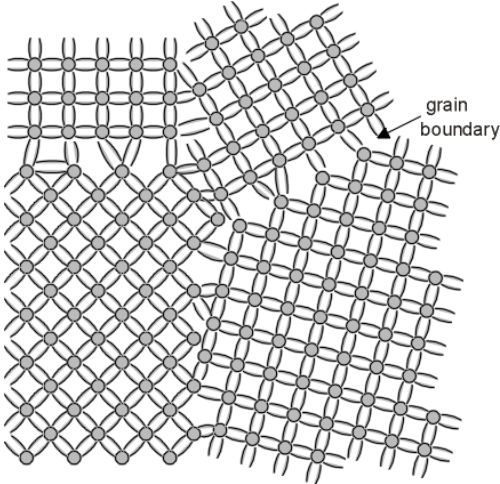
Polycrystalline and multicrystalline Si – cost reduction

Multicrystalline
grain size ~ layer thickness (mm)
2-3% less efficiency,
80% costs

*Methods:
casting
ribbon growth
thin film deposition ...*



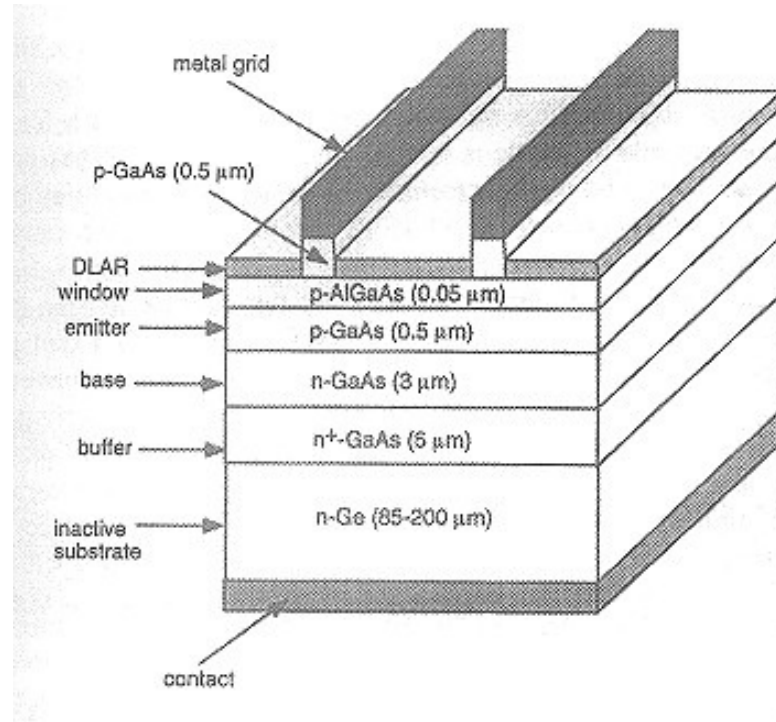
Polysilicon Ingots



Polycrystalline:
recombination via grain boundaries important

Single crystal GaAs cell, η up to 25%

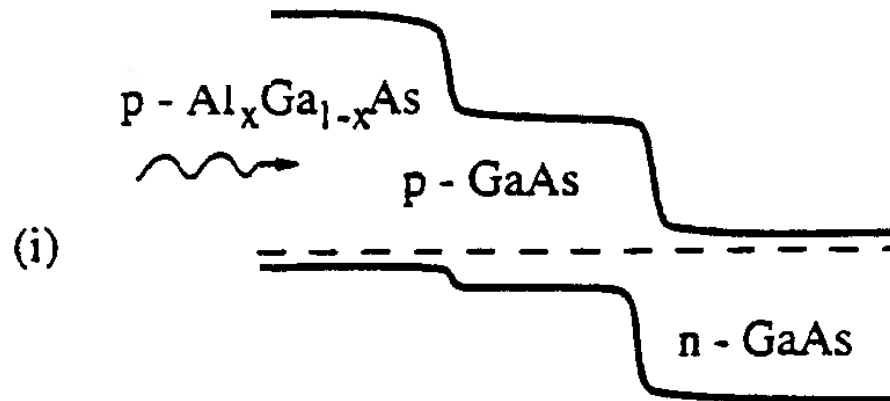
Space applications



Direct bandgap, $E_g=1.42$ eV closer to optimum
absorption $\alpha \sim 10\text{-}100$ x higher than in Si

↓
much thinner layer

COSTS!



Higher bandgap in the emitter → reduced surface recombination

Applications of GaAs-based cells

✓ Space applications:

lightweight,

more radiation-resistant

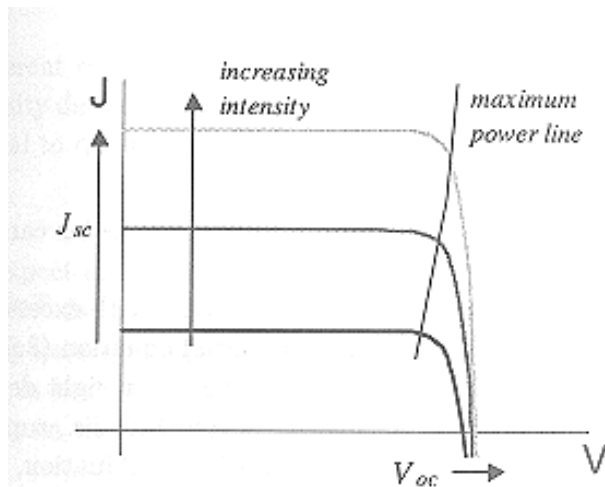
✓ Under concentrated light:

lower probability of Auger recombination

better thermal coefficient

	Emitter n-type	Base p-type
thickness	0.5 μm	4 μm
doping	10^{18} cm^{-3}	10^{17} cm^{-3}
minority carrier diffusion length	1.4 μm	3 μm
minority carrier lifetime	10^{-9} s	10^{-8} s

Efficiency increase under concentration

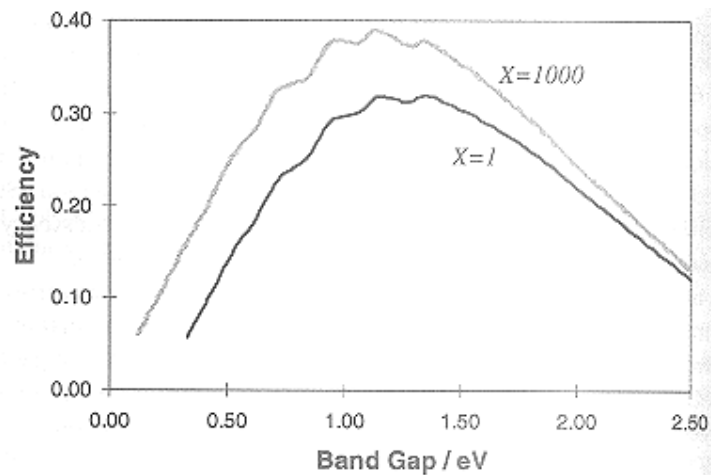


record cells

GaAs 27.6% under 255 suns

Si 26.8% under 90 suns

under concentration optimum bandgap is lower



GaAs is still better than Si:

1. lower thermal coefficient
2. lower probability of Auger recombination under concentrated light